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## INFORMATION DISCLOSURE STATEMENT

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1762

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS
MBC	1	GB 2 077 710 A	12/23/1981	Great Britain	—	—
MBC	2	JP-A 64-029661 w/ Abstract	01/31/1989	Japan	—	—
MBC	3	JP-A 09-237927 w/ Abstract and translation	09/09/1997	Japan	—	—
MBC	4	JP-A 63-111454 w/ Abstract	05/16/1988	Japan	—	—
MBC	5	JP-A 10-321536 w/ Abstract and translation	12/04/1998	Japan	—	—

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

MBC	6	"Advances in deposition Processes for Passivation Films", W. Kern et al., <i>J. Vac. Sci. Technology</i> , 14, 1082, ©1977. -1099
MBC	7	"Substitutional doping of Amorphous Silicon", W. E. Spear et al., <i>Solid State Communications</i> , 17, 1193, ©1975. -1196

EXAMINER

DATE CONSIDERED

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Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: July 29, 2004